

PATTERN INSPECTION DEVICE

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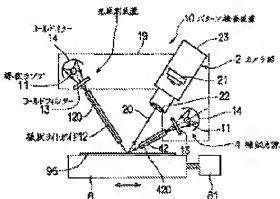
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Abstract of JP7333169

PURPOSE: To provide a pattern inspection device capable of emitting light of uniform and high illuminance to the pattern of an inspected body, ensuring the body and a plate type light guide to be free from thermal damage, and performing accurate pattern inspection.

CONSTITUTION: A pattern inspection device 10 has a light emitting device 1 for illuminating the pattern of an inspected body 96 and a camera section 2 for photographing the pattern. In addition, the device 10 is provided with a rod type lamp 11 for a light source, a plate type light guide 12 for introducing the light of the lamp 11 toward the body 96, a cold filter 13 laid between the guide 12 and the lamp 11, and a cold mirror 14 laid behind the lamp 11.



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